

# **“The 37<sup>th</sup> European Mask and Lithography Conference”**

**EMLC 2022**

**will take place**

**Monday, June 20<sup>th</sup> – Wednesday, June 22<sup>nd</sup>, 2022**

**at the**

**KU in Leuven, Belgium**



**Jubilee Hall for Exhibition & Posters**



**Conference Room**

**TUTORIAL**



**Peter De Bisschop**  
IMEC



**Rogier Verberk**  
TNO

**EMLC 2022**  
Already  
Confirmed  
Presentations

**KEYNOTE**



**Luc Van den Hove**  
IMEC



**Frank E. Abboud**  
INTEL



**Jos Benschop**  
ASML

**INVITED**



**Ingo Bork**  
Siemens EDA



**Jo Finders**  
ASML



**Michael Haberler**  
IMS Nanofabrication



**Dirk Hellweg**  
Carl Zeiss SMT



**Vicky Philipsen**  
IMEC



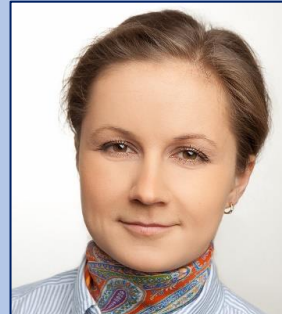
**Heike Riel**  
IBM Research



**Thomas Schmidt**  
AMTC



**Frank Sundermann**  
ST Microelectronics



**Anna Tchikoulaeva**  
Lasertec



**Raluca Tiron**  
CEA LETI



**Taguhi Yeghoyan**  
YOLE

**Best Paper of  
PMJ 2022**  
(to be defined)

**BACUS 2021**  
1<sup>st</sup> Place  
Student Paper:  
ZEISS Award



**Luke T. Long**  
UC Berkeley

**BACUS 2021**  
1<sup>st</sup> Place  
Student Paper:  
Photronics Award



**Mazem Mesilhy**  
Fraunhofer IISB



# Tuesday, June 21<sup>st</sup>, 2022

## Conference Dinner at the Faculty Club



**Thursday, June 23<sup>rd</sup>, after EMLC 2022: Visit at**



**Organized by Kurt Ronse**

**Director Advanced Patterning Program at imec**

**and**

**Uwe Behringer**

**UBC Microelectronics, EMLC2022 Conference Chair**

**ABSTRACT DUE DAY: April 15<sup>th</sup>, 2022**

**[www.emlc-conference.com](http://www.emlc-conference.com)**